

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): ZAIT, Eitan, et al.      Examiner: FRASER, Stewart A.  
Serial No.: 10/564,972      Group Art Unit: 2625  
Filed: August 1, 2006      Confirmation No. 7182  
Title: METHOD FOR CORRECTING CRITICAL DIMENSION VARIATIONS IN PHOTOMASKS

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**Mail Stop RCE**  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Sir:

This Amendment is being filed in response to the final Office action dated August 11, 2009 issued by the United States Patent and Trademark Office in connection with the above-identified Application. A response to the August 11, 2009 final Office action was due November 11, 2009. Applicants are concurrently filing a Petition for a Two-Month Extension of Time, including the required fee. Therefore, a response is due January 11, 2009. Accordingly, this Amendment is being timely filed. A request for continued examination is also concurrently being filed, including the required fee.

Kindly amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.